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PATENT AND TRADEMARK OFFICE

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**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

(Use several sheets if necessary)

37 CFR 1.98(b)

APPLICANT
Xavier Jean-François LEVECO et al.

FILING DATE
November 2, 2001

GROUP
2877

U.S. PATENT DOCUMENTS

EXAMINER INITIAL	PATENT NO.	ISSUE DATE	PATENTEE	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
	AA					
	AB					
	AC					
	AD					
	AE					
	AF					

FOREIGN PATENT OR PUBLISHED FOREIGN PATENT APPLICATION

	DOCUMENT NO.	PUBL. DATE	COUNTRY OR PATENT OFFICE	CLASS	SUB CLASS	TRANSLATION YES
DBE	AI 197 05 119 A1	08/98	DE			With English summary
	AJ					
	AK					
	AL					
	AM					
	AN					

OTHER DOCUMENTS (Including Author, Title, Date, Relevant Pages, Place of Publication)

DBE	AT	Michael C. Roggemann et al., "Algorithm to Increase the Largest Aberration that Can be Reconstructed from Hartman Sensor Measurements," <u>APPLIED OPTICS</u> , v. 37, 1998, PP. 4321-4329.
	AU	
	AV	
	AW	

EXAMINER

D. Bigler

DATE CONSIDERED

4/9/03

EXAMINER: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.